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CERTIFICATE OF Applicant(s): Cline et al.	TRANSMISSION BY FAC	SIMILE (37 CFR 1.8)		Docket No. BUR920040122US1
Application No. 10/711,953	Filing Date 10/15/2004	Examiner Chen, Eric Brice		Group Art Unit 1765
Invention: DEEP TRENCH FORMATION IN SEMICONDUCTOR DEVICE FABRICATION				
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## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Cline et al.

Examiner: Chen, Eric Bricc

Serial No.:10/711,953

**Art Unit: 1765** 

Filed: 10/15/2004

Docket No.: BUR920040122US1

Title: DEEP TRENCH FORMATION IN SEMICONDUCTOR DEVICE FABRICATION

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

## Request for Reconsideration

Sir:

This Request for Reconsideration is in response to the Office Action mailed September 7, 2005.